

1758

Docket No.: 645-145



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
PATENT OPERATION

In re Application of:
Akira **MASUMURA**

Serial No.: 09/872,842

Filed: June 1, 2001

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Group Art Unit:-- 1755

Examiner:-- S. Coles

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For: **OPTICAL GLASS SUFFERING LITTLE CHANGE IN REFRACTIVE
INDEX BY RADIATION LIGHT**

New York, NY 10036
Date: April 3, 2002

Commissioner for Patents
Washington, DC 20231

INFORMATION DISCLOSURE STATEMENT

RECEIVED
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SIR:

Request is hereby made for consideration of
this information disclosure statement. The following
references are being cited under the provisions of 37 CFR
§ 1.97.

EP Search Report

Lists references cited
by EP Examiner.

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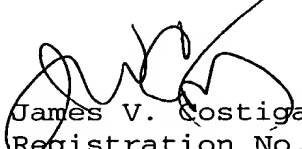
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Discloses the optical
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glasses for micro-
lithography.

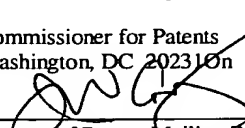
Respectfully submitted,


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